# WP5: Activities on TPSCo 65 nm process

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#### **Outline**

- Introduction
- ■Revisiting 1st TPSCo 65 nm submission
  - CE-65 sensor design and tests
- **ER1** submission
  - MOSS design and test
  - CE65v2 design and test
- ■Summary and outlook

#### People involved in CE65 sensors

**IPHC:** A. Kumar, A. Dorokhov, S. Bugiel, J. Baudot, A. Besson, C. Colledani, Z. El Bitar, M. Goffe, C. Hu-Guo, K. Jaaskelainen, S. Senyukov, H. Shamas, I. Valin, Y. Wu(USTC)

**Zürich:** E. Ploerer, A. Ilg, A. Lorenzetti, A. Macchiolo

Prague: P. Stanek, L. Tomasez, A. Kostina

Hiroshima: Y. Yamaguchi, T. Katsuno

Tokyo: H. Baba, T. Gunji

Tsukuba: T. Chujo, J. Park, D.Shibata, S.Sakai

Larger community contributed globaly on TPSCo 65 nm development (backup slide 20)

# **WP5 Requirements**

-- Goal of WP5 is to develop high granular and radiation hard depleted monolithic active pixel sensors

Sensor spatial resolution	$\begin{split} \sigma_{sp} &\lesssim 3~\mu\text{m} \to \text{for Higgs-factories} \\ &\sim 5~\mu\text{m} \to \text{for ALICE} \\ &\sim 5\text{-}10~\mu\text{m} \to \text{for Belle II} \end{split} \qquad \Leftarrow \text{critical benefit of small} \\ &\text{in 65nm for task 5.2} \\ \end{split}$	
Hit rate and time resolution (depends on experiment)	<ul> <li> few 10 MHz/cm²/s for Higss-factories</li> <li> 100 MHz/cm²/s for Belle II</li> <li> Time resolution ~ns for CLIC</li> <li> time resolution in 10-100ps range</li> <li>(Specific for PID or 4D tracking)</li> </ul>	<ul> <li>← requires new readout architectures, critical for both tasks 5.2+5.3</li> <li>← benefit of thin sensitive layer in 65nm, critical for task 5.3</li> </ul>
Radiation tolerence and NIEL fluence	Up to $10^{12}$ $n_{eq(1MeV)}/cm^2$ for task 5.2 Mimimum $10^{15}$ $n_{eq(1MeV)}/cm^2$ and beyond for task 5.3	← 65nm tolerance to be checked,     critical for task 5.3

## Roadmap

- 1st submission: MLR1 re-AIDAinnova
  - Test structures + Functional blocs
  - Various pixel structures
  - Design work
- 2023
- Preparation for ER2
  - ALICE-ITS3 stitched sensors
  - Still some chiplets

2024

2025

- 3<sup>nd</sup> submission Q4: ER2
- Preparing 4<sup>th</sup> submission: MPR2
  - Large prototype addressing future vertex detectors & trackers
  - New ideas (amplification, ...)
- Preparation for MPR2 (Q4 2024)
  - Seeds to ECFA-DRD3/7 projects

- 2nd submission: ER1
  - Test structures + Functional blocs

2021-2022

- Various pixel structures
- 1st stitched sensor
- Testing work
  - Finalise tests on MLR1
  - Start ER1 tests
    - 1st test on stitched sensors
    - Tests on chiplets

- Finalise tests on ER1
- · Preparartion of ER2 tests
- Tests of ER2 may not start before end-of-AIDAinnova

Activities in synergy with CERN EP R&D WP1.2 & ALICE-ITS3

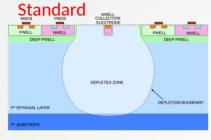
- Question addressed
  - ⇒ Techno validation
  - · Yield with stitching
  - Handling/bending of thin & large (<100cm²) area</li>
  - Performance optimisation (space & time resolution)
    - ⇒ Techno exploration
  - OUTCOME of AIDAinnova
    - Readiness for ALICE-ITS3
    - Readiness for future plans

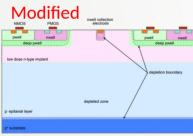
Slide: Jerome Baudot

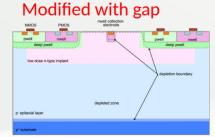
#### MLR1: Recap on 1st TPSCo submission

#### standard + 2 modified for better depletion

- -- "modified": low dose n-type blanket
- -- "modified with gap": same as above + gap on pixel edge.







#### **APTS (Analogue Pixel Test Structure)**

- 6×6 pixel matrix
- Direct analogue readout
- 4 pitches: 10, 15, 20, 25 μm
- 3 process variations

#### **Ref: APTS**



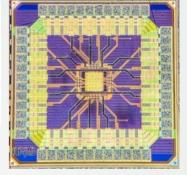
- 2 matrix sizes (64x32 & 48x32)
- Rolling shutter readout
- 2 pitches: 15, 25 μm

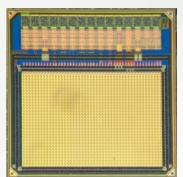
#### **Ref: CE65**

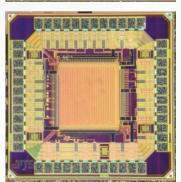
#### **DPTS (Digital Pixel Test Structure)**

- 32×32 pixel matrix
- Asynchronous digital readout
- Time-over-Threshold information
- pitche: 15μm
- -Only "modified with gap" process modification

#### **Ref: DPTS**



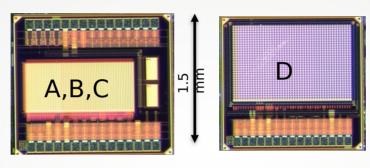


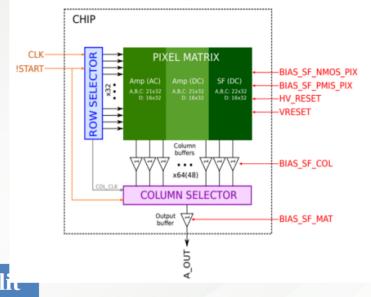


## CE-65 Sensors (v1)

#### **Contribution from IPHC**

- Analogue output
- Rolling shutter readout
- Readout 10 to 40 MHz





Variant	Pitch	Matrix size	Front-ends	Collection diode structure	Split	
A	15 μm	64x32	DC-SF, DC-Amp, AC-Amp	Standard	1-4	
В				Blanket w gaps		
С				Blanket		
D	25 μm	48x32	•	Basic		

Note: AC-coupled frontend allows sensitive volume biasing without backside voltage

#### Results from CE65v1 testbeam

**Telescope and DAQ:** 

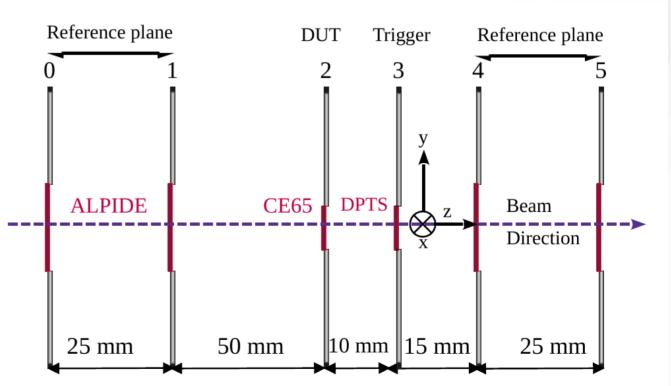
Reference Arms: 4 ALPIDE planes for track reconstruction

**DUT:** CE65 **TRG:** DPTS

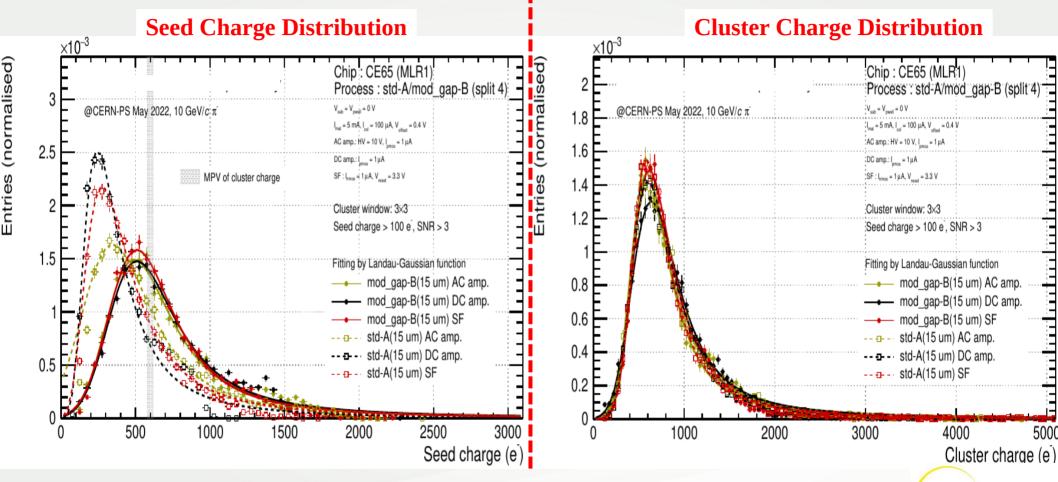


#### Test beam:

- -- EUDAQ2
- -- Analysis using corryvreckan
- -- May 2022 at CERN-PS
- -- 4 frames for each event
- -- Pedestal map Noise map
- -- Calibration file



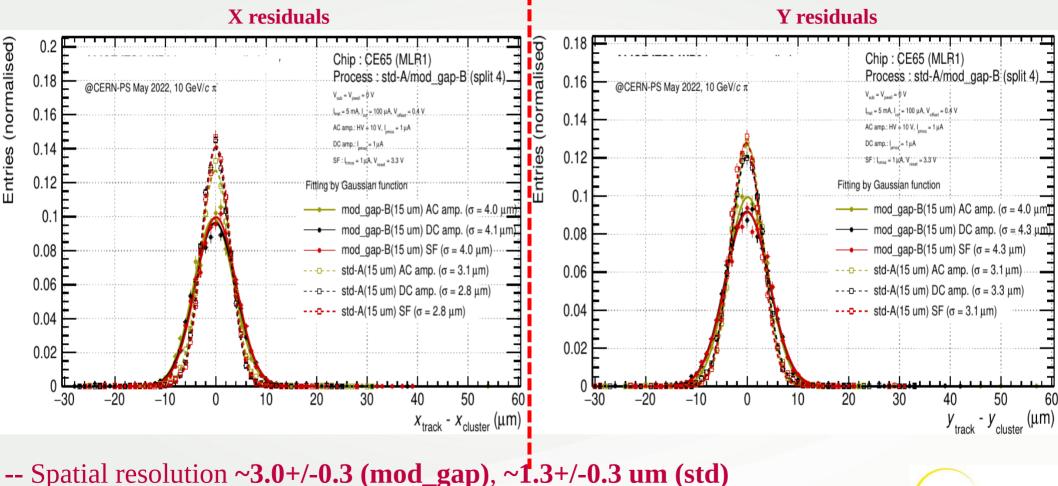
# Comparing charge sharing ('std' and 'mod\_gap')



-- Charge sharing is large in "std" compare to "mod\_gap".



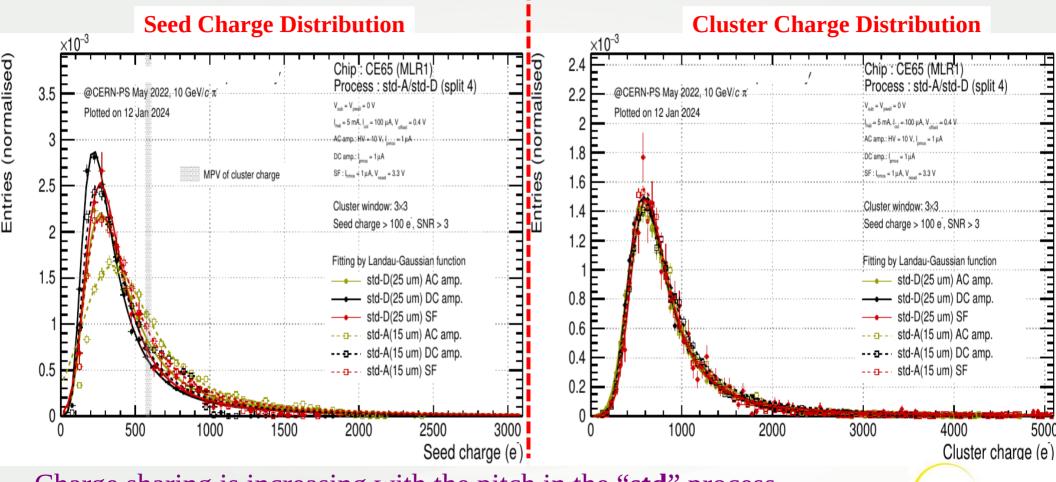
# Comparing residuals ('std' and 'mod\_gap')



-- **modified** process makes us loose about 1.7 um for the same pitch of 15 um.



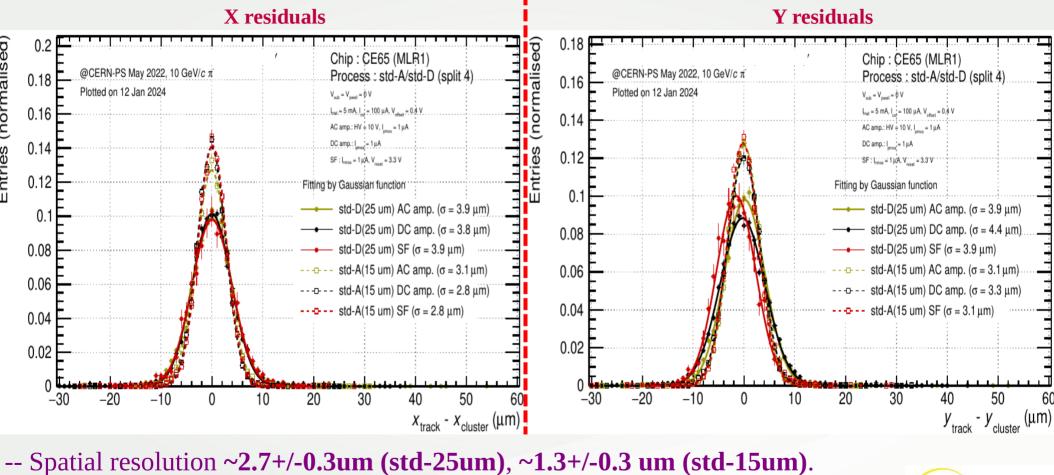
# Comparing charge sharing (15um and 25um for 'std')



-- Charge sharing is increasing with the pitch in the "**std**" process (contrary to "**modified**" process) ---- diffusion dominate depletion!



# Comparing residuals (15um and 25um for 'std')



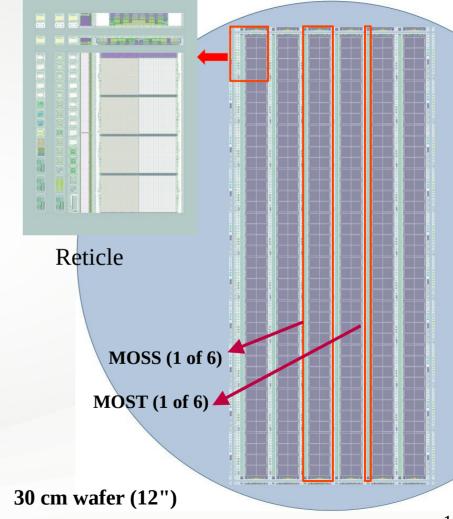
-- **DPTS** with **modified** process and **15 um pitch:** about 4 to 4.2 um

-- We loose about 1.4 um from 15 to 25 um



## **ER1 submission**

- Learn and prove stitching-Methodology, Constraints, Yield
- -- "**MOSS**": 14 x 259 mm, 6.72 MPixel (22.5 x 22.5 and 18 x 18 μm2)
  - conservative design, different pitches
- "MOST": 2.5 x 259 mm, , 0.9 Mpixel (18 x 18 µm2)
  - more dense design, higher power granularity
- -- Small prototype and test chips (like MLR1)
  - Pixel Prototypes (New versions of APTS, DPTS, CE65(v2) )
  - Fast Serial Links, PLL, I/Os, SEU



#### CE-65 Sensors (v2)

- AC-coupled only
- three types (STD, GAP, BLANKET)
- pitches (15um, 18um, 22.5um)
- geometry (regular and staggered)
- option for window readout

- Tested at **DESY** in **Nov. 2023**
- planned to test at SPS in Apr. 2024 (mainly to study apatial resolution)
  - planned to test at **DESY** in **May 2024** (Irradiation study)

#### Pitch / process

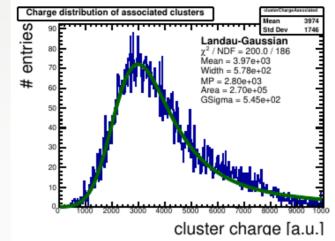
				3 GeV	4 GeV	5 GeV
22.5	GAP	SQ	PCB08	10V & 4V (50k ev)		10V (90k events)
18	GAP	SQ	PCB02	10V (17k ev)	10,4 & 0V (55k Ev) & 2V (~30k)	
15	GAP	SQ	PCB19		10,4,2 & 0V (75k Ev)	
22.5	GAP	HSQ	PCB05		10,4,2 & 0V (50k Ev)	
18	GAP	HSQ	PCB03		10,4,2 & 0V (85k Ev)	
22.5	STD	SQ	PCB18		10,4,2 & 0V (50k Ev)	
15	STD	SQ	PCB06		10,4,2 & 0V (85k Ev)	
18	STD	SQ	PCB23		15, 10, 4 & 0V (55k Ev)	
					10V (100k Ev) 4,2 & 0V (50k	
22.5	GAP	SQ	PCB07		Ev) + 3 frames mode (50k Ev)	

Test done at DESY, Nov. 2023

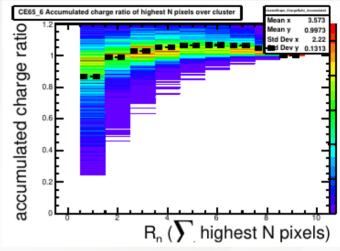
#### CE65v2 test beam

**Cluster Distribution** 

- -- Tested at DESY in November 2023
- -- ALPIDE telescope
- -- Beam e<sup>-</sup>4GeV
- -- Analysis with Corry cluster (3x3)
- -- Modified with gap
- -- Square pixels
- -- Pitch → 22.5 um

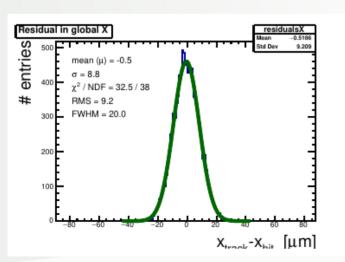


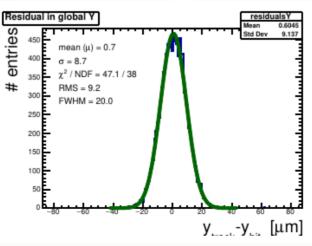




Very small charge sharing

- --  $\sigma$  of residuals is large
- -- investigation is ongoing
- -- detailed analysis for all the runs is underway





# **MOSS** design

-- 10 repeated sensor units (RSU)

- 1.4 x 26 cm monolithic stitched sensor

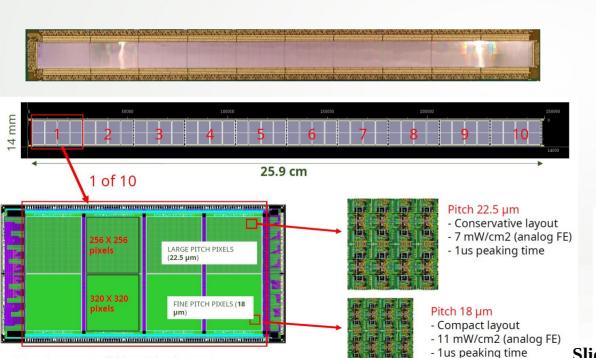
- -- top and bottom halves with different pitch (18 and 22.5 um)
- -- 4 different sub-matrices. 6 different analogue designs, 3 of the bottom regions have the same FE
- CERN

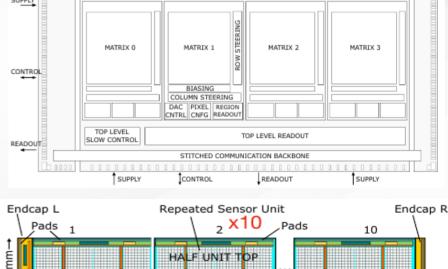


1.5 mm

16

- -- Each half RSU can be tested independently
- -- Stitched "back-bone" allows to control and readout the sensor from left short side





HALF UNIT BOTTOM

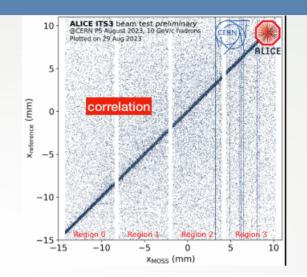
Peripheral circuits

MOSS HALF UNIT

**Slide:** Magnus Mager (CERN) | HSTD13 | 07.12.2023

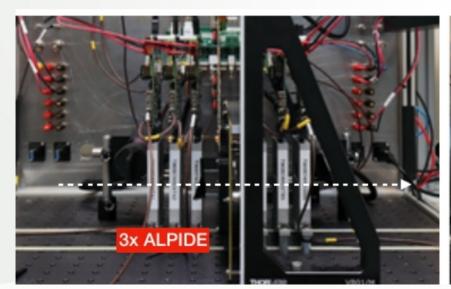
#### **MOSS** test beams

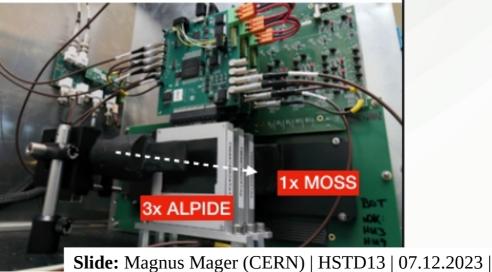
- -- Several test beams in 2023
- -- Parameters still to be optimised and detailed data analysis is ongoing
- -- Very encouraging results



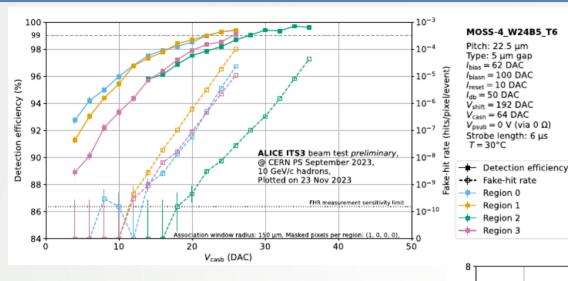








#### MOSS test beams...





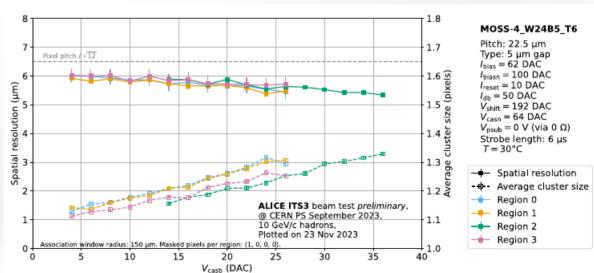


#### Efficiencies and fake hit rate

NB: analogue bias settings are still being optimised

# **Spatial resolution and cluster size**

-- matches with those of small prototypes



**Slide:** Magnus Mager (CERN) | HSTD13 | 07.12.2023 |

# **Summary and outlook**

- TPSCo 65 nm is validated for detection and stitching seems doable.
- Full characterization of MOS-S and MOS-T needed to assess more precisely (yield) stitching
- Stitching
- CE-65 sensor family focuses on charge sharing & position resolution studies
   Position resolution behaviour with pitch & process modification qualitatively understood
- with charge sharing
- TCAD & Allpix2 on-going for quantitative intepretation
- > 25 um pitch in standard process using full analogue information yields better resolution (~2.7 um against ~4 um) than 15 um pitch with binary output in modified process
- CE65v2 was tested at DESY. Preliminary results are shown. Detailed analysis is underway
- ➤ Planned to test CE65v2 sensors:

  ➤ Studying spatial resolution at **SPS in April 2024** . Important to compare for various **pitch** 
  - and pixel geometries (regular & staggered)

    Thank you for your kind attention!

# **Backup slides**

# Large collaboration

#### Many contributors

Birmingham University: L. Gonella, P. Allport

Bolu University: K. Ovulmaz

Talinn University: K. Rebane (also with CERN)

Zagreb University: T. Suligoj, D. Dobrijevic (also with CERN)

Yonsei University: Y. Kwon, G.H. Hong CCNU: Wenjing Deng (also with CERN) EPFL: E. Charbon, F.Piro (also with CERN)

CERN: G. Aglieri Rinella, I. Asensi Tortajada, W. Bialas, G. Borghello, R. Ballabriga, J. Braach, E. Buschmann, M. Campbell, F. Carnesecchi, L. Cecconi, F. Dachs, D. Dannheim, V. Dao, K. Dort, Joao de Melo, W. Deng (also with CCNU), A. Di Mauro, D. Dobrijevic, A. Dorda Martin, P. Dorosz, L. Flores Sanz de Acedo, A. Gabrielli, G. Gustavino, J. Hasenbichler (also with TU Vienna), H. Hillemans, J. Kremastiotis, A. Kluge, T. Kugathasan, M. LeBlanc, P. Leitao, M. Mager, P. Martinengo, M. Munker (now with U. Geneva), L. Musa, H. Pernegger, F. Piro, K. Rebane (also with Talinn University), F. Reidt, P. Riedler, I. Sanna (also with TU Munich), A. Sharma, W. Snoeys, C. Solans, M. Suljic, G. Termo M. Vicente (now with U. Geneva), J. Van Rijnbach (also with Oslo U.)

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Savino, S. Perciballi, F. Prino, A. Turcato

University and INFN Bari: G. De Robertis, F. Loddo University and INFN Catania: P. La Rocca, A. Triffiro

University and INFN Cagliari: D. Marras, G. Usai, S. Siddhanta

University of Salerno: R. Ricci

University and INFN Trieste: M. Buckland, G. Contin

IPHC: J. Baudot, G. Bertolone, A. Besson, R. Bugiel, S. Bugiel, C. Colledani,

A. Dorokhov, Z. El Bitar, X. Fang, M. Goffe, C. Hu, K. Jaaskelainen, F.

Morel, H. Pham, S. Senyukov, J. Soudier, I. Valin, Y. Wu (also with USTC) CPPM: P. Barrillon, M. Barbero, D. Fougeron, A. Habib, P. Pangaud

NIKHEF: R. Russo, V. Gromov, D. Gajanana, A. Yelkenci, A. Grelli, R. Kluit, J.

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Heidelberg University: H.K. Soltveit, P. Becht, A. Yuncu

Prague University: A. Isakov, F. Krizek

Technical University Munich: L. Lautner, I. Sanna (also with CERN)

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Gregor, K. Hansen, L. Huth, B. Mulyanto, C. Reckleben, S. Ruiz Daza, P. Schütze, A. Simancas, S. Spannagel, M. Stanitzki, A. Velyka, G. Vignola, H.

Wennlöf

Technical University Vienna: J. Hasenbichler (also with CERN)

STFC (RAL): A. Hodges, S. Matthew, I. Sedgwick

Oxford University: D. Bortoletto, F.Windischofer (also with CERN)

#### **ER1** submission

# **ER1 Submission (12/2022)**

#### Learn and prove stitching

Methodology, Constraints, Yield

"MOSS": 14 x 259 mm, 6.72 MPixel (22.5 x 22.5 and 18 x 18 µm<sup>2</sup>)

conservative design, different pitches

"MOST": 2.5 x 259 mm, , 0.9 MPixel

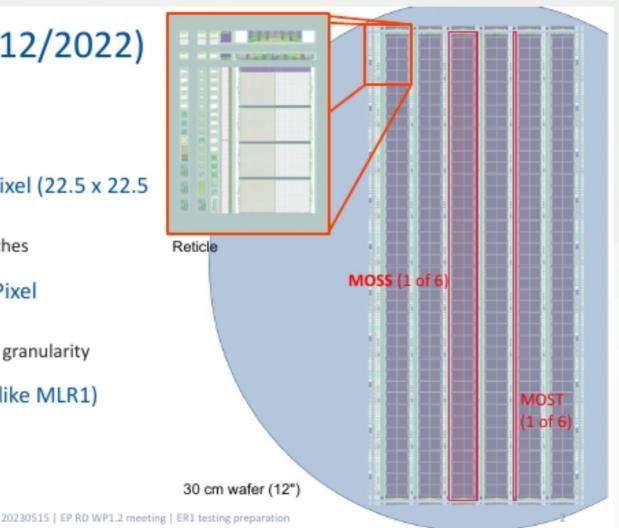
(18 x 18 μm²)

more dense design, higher power granularity

#### Small prototype and test chips (like MLR1)

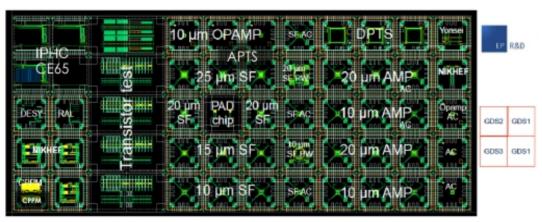
Pixel Prototypes

Fast Serial Links, PLL, I/Os, SEU



#### Recap on 1st submission

- Multi-Layer Reticule (MLR1)
  - 5 metal layers, HR thin (~10µm) epi layer

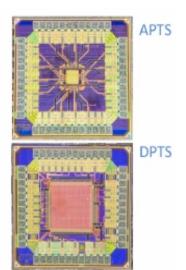


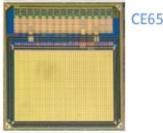
- IPHC: rolling shutter larger matrices, DESY: pixel test structure (using charge amplifier with Krummenacher feedback, RAL: LVDS/CML receiver/driver, NIKHEF: bandgap, T-sensor, VCO, CPPM: ring-oscillators, Yonsei: amplifier structures
- Transistor test structures, <u>analog pixel (4</u>x4 matrix) test matrices in several versions (in collaboration with IPHC with special CERN amplifier), <u>digital pixel test</u> matrix (DPTS) (32x32), pad structure for assembly testing.
  - After final GDS placement, GDS1 is instantiated twice.
  - Converged with 4 splits of 3 wafers



- 10-25 µm pitch
- APTS = analogue outputs with OpAmp
- DPTS = digital outputs

 CE65 = analogue outputs with DC/AC and no-Amp/Amp





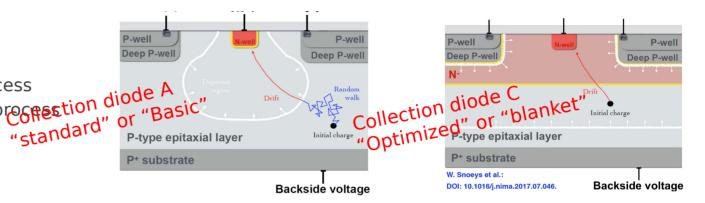
Slide: Jerome Baudot

# TPSCo 65nm process modification

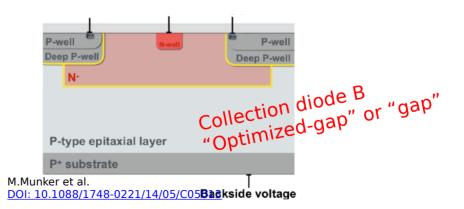


- 4 process splits
  - Doping modifications:
    - 1. Default process
    - 2. First intermediate process
    - 3. Second intermediate process

      1. Ontiminal
    - Optimized process



- 3 collection diode structures
  - Following successful modifications in Tower 180 nm
  - Standard => Optimized(gap) structures
- ⇒ Both modifications based on TCAD studies
  - Stll on-going for subsequent submissions



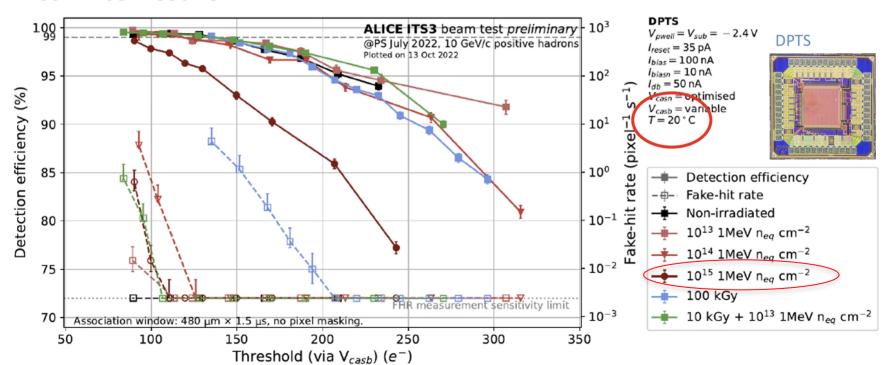
# MLR1 findings



Promising radiation tolerance

S.Perciballi @ TREDI2023 <a href="https://indi.to/yD2ZF">https://indi.to/yD2ZF</a>

- DPTS (digital) with 15 μm pitch
- Beam test results





# MLR1 findings



#### **Timing resolution**

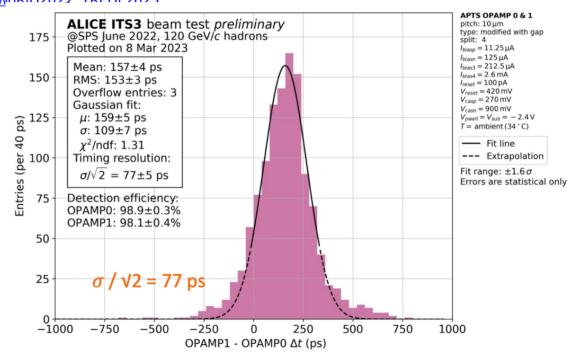
C. Ferrero @ TWEPP 2023

• Based on APTS, CE-65, DPTS: talks at IWARID2022 TREDI 2023

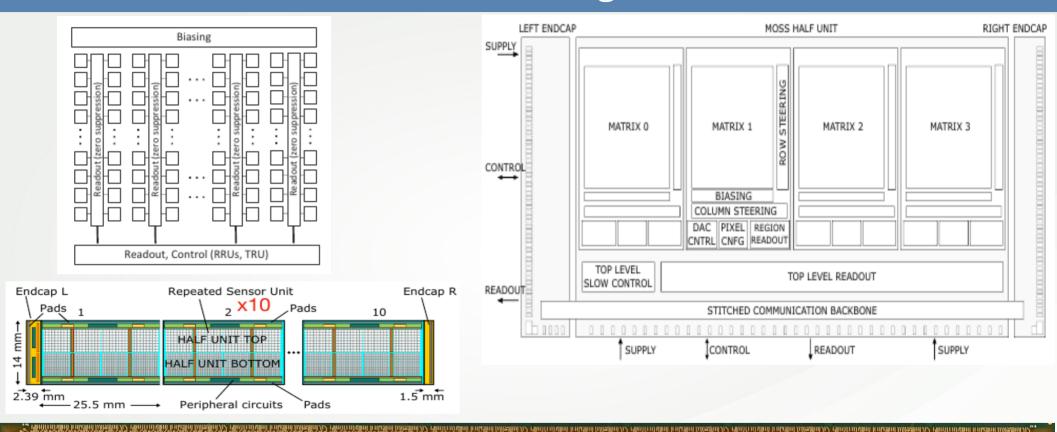
**ULTIMA 2023** 

Variety of pixel pitches: 10-25 μm

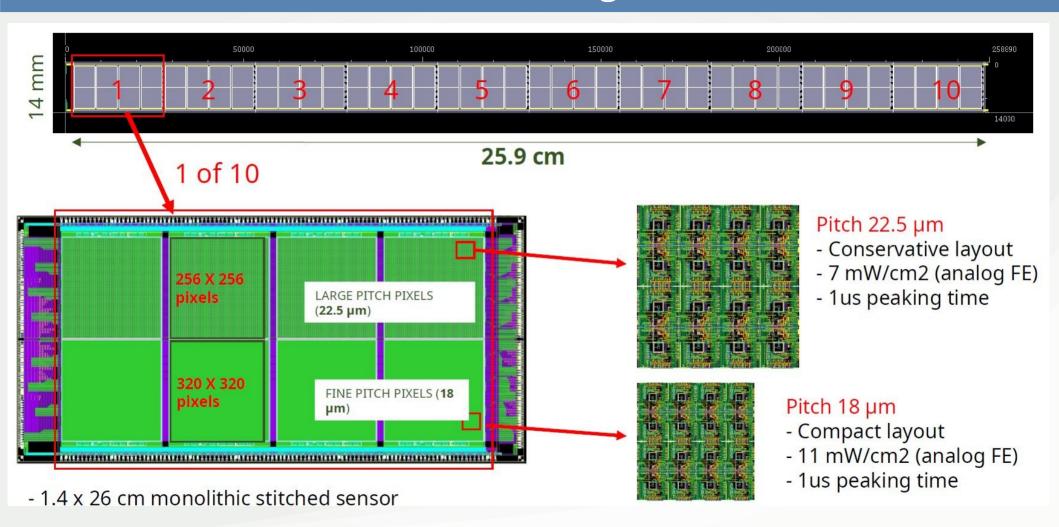
- Successful sensitive layer depletion
- Promising radiation tolerance
- Promising time resolution



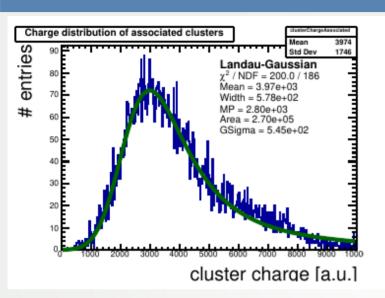
# **MOSS** design

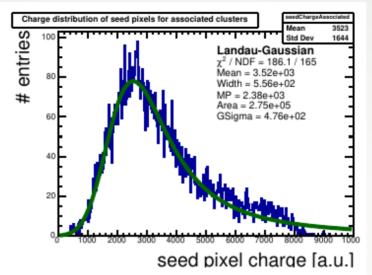


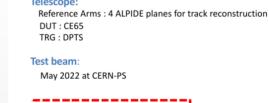
#### **MOSS** design



#### CE65v2 test beam





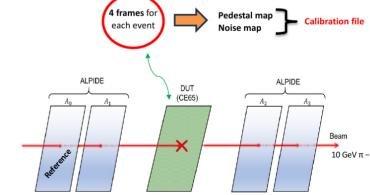


Data acquisition:

framework: Corryvreckan

Noise run-Beam run: correlated double sampling method (CDS)

EVENT reconstruction algorithm and data analysis



7.5

2.5

Support provided by Alice Collaboration

12.5

Z (cm)

CE65v1 setup